

ASSIGNMENT

Whereas, we,

INVENTOR  
AND CITY

Amanda Baer, of Campbell, County of Santa Clara, State of California,  
 Marie-Claire Cyrille, of San Jose, County of Santa Clara, State of California,  
 Frederick Hayes Dill, of South Salem, County of Westchester, State of New York,  
 Benjamin Lu chen Wang, of San Jose, County of Santa Clara, State of California,  
 Cherngye Hwang, of San Jose, County of Santa Clara, State of California, and  
 Mustafa Finarbasi, of Morgan Hill, County of Santa Clara, State of California

have invented certain improvements in

TITLE

METHOD OF FORMING A READ SENSOR USING PHOTORESIST STRUCTURES WITHOUT UNDERCUTS WHICH  
 ARE REMOVED USING CHEMICAL-MECHANICAL POLISHING (CMP) LIFT-OFF PROCESSES

 DATES THAT  
 INVENTORS  
 SIGNED THE

and executed, respectively, a United States patent application therefor on

(1) 9/26/03 (2) 9/26/03 (3) 9/30/03 (4) 9-30-03  
 (5) 9/26/03 (6) 9/26/03

Whereas, HITACHI GLOBAL STORAGE TECHNOLOGIES NETHERLANDS, B.V., having a place of  
 business at Locatellikade 1, 1076 AZ Amsterdam, The Netherlands (hereinafter called  
 HITACHI), desires to acquire the entire right, title and interest in the said  
 application and invention, and to any United States and foreign patents to be obtained  
 therefor;

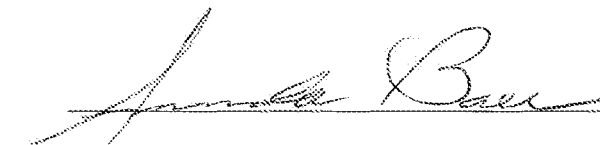
Now therefore, for a valuable consideration, receipt whereof is hereby  
 acknowledged, we, the above named, hereby sell, assign, and transfer to HITACHI, its  
 successors and assigns, the entire right, title and interest in the said application  
 and invention therein disclosed for the United States and foreign countries, and all  
 rights of priority resulting from the filing of said United States application, and we  
 request the Commissioner of Patents to issue any Letters Patent granted upon the  
 inventions set forth in said application to HITACHI, its successors and assigns; and  
 we hereby agree that HITACHI may apply for foreign Letters Patent on said invention  
 and we will execute all papers necessary in connection with the United States and  
 foreign applications when called upon to do so by HITACHI.

Signed and sealed

CITY

(1) at San Jose

DATE

on 9/26, 2003
  
 Amanda Baer

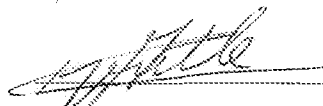
SIGNATURE

INVENTOR

CITY

(2) at San Jose

DATE

on 9/26, 2003
  
 Marie-Claire Cyrille

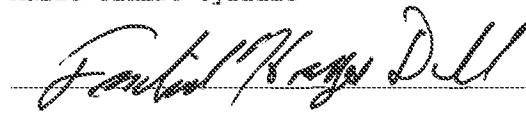
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INVENTOR

CITY

(3) at San Jose

DATE

on 9/30, 2003.
  
 Frederick Hayes Dill

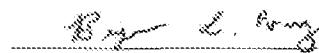
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INVENTOR

CITY

(4) at San Jose

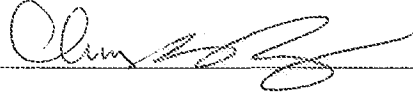
DATE

on 9-30, 2003
  
 Benjamin Lu chen Wang

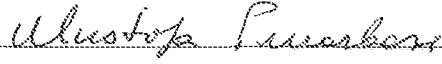
SIGNATURE

INVENTOR

CITY (5) at San Jose  
DATE on 9-26, 2003

 SIGNATURE  
Cherngye Hwang INVENTOR

CITY (6) at San Jose  
DATE on 9-26, 2003

 SIGNATURE  
Mustafa Pinarbasi INVENTOR